

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10010548	11/08/2001	216	63	1740	Tran, KB

**APPLICANTS: Yeom Geun-Young; Lee Do-Haing;

1765

**CONTINUING DATA VERIFIED:

None BT

BEST AVAILABLE COPY

** FOREIGN APPLICATIONS VERIFIED:

REPUBLIC OF KOREA 2000-69660 11/22/2000

BT

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed

☒ yes ☐ no

35 USC 119 conditions met

☐ yes ☒ no

Verified and Acknowledged Examiners's initials

BT

ATTORNEY DOCKET NO

YPL-0022

TITLE : Method of etching semiconductor device using neutral beam and apparatus for etching the same

U.S. DEPT. OF COMM. / PAT. & TM. PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED

Amount Due Date Paid

ISSUE FEE

Amount Due Date Paid



TERMINAL

DISCLAIMER

Assistant Examiner

Primary Examiner

PREPARED FOR ISSUE

CLAIMS ALLOWED

Total Claims

Print Claim for
O.G.

DRAWING

Sheets Drawn

Figs. Drawn

Print Fig.

Application Examiner

WARNING: The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code, Title 35, Sections 122, 181 and 368, Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.

FILED WITH:

☐ DISK (CRF)

☐ CD-ROM

(Attached in pocket on right inside flap)